



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 5686**  
Mitsuo SAITOH et al. : Docket No. 2003\_1228A  
Serial No. 10/649,670 : Group Art Unit 1763  
Filed August 28, 2003 : Examiner Allan W. Olsen

PLASMA PROCESSING METHOD  
AND APPARATUS

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEES FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

**RESPONSE TO RESTRICTION REQUIREMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Restriction Requirement of August 12, 2005, Applicants hereby elect Group I, which is drawn to a plasma processing method and is embodied by claims 1-8.

Having made the required election, a full examination on the merits of the elected group is requested.

Respectfully submitted,

Mitsuo SAITOH et al.

By: Michael S. Huppert

Michael S. Huppert  
Registration No. 40,268  
Attorney for Applicants

MSH/kjf  
Washington, D.C. 20006-1021  
Telephone (202) 721-8200  
Facsimile (202) 721-8250  
September 8, 2005